

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:

Matthew Prince et al.

Serial No.:

10/762,849

Filed:

January 22, 2004

For:

Reducing Wafer Defects from

Chemical Mechanical Polishing

Art I

Art Unit:

3723

Examiner:

Hadi Shakeri

Docket:

ITL.0941US

P15694

Assignee:

Intel Corporation

Mail Stop RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to the receipt of an Office action for the above-referenced patent application, please amend the claims as follows:

Date of Deposit: February 13, 2006

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Nancy Meshkoff